

AMENDMENTS TO THE SPECIFICATION

Paragraph [0026] on page 7 of the electronically filed specification is amended to read as follows:

Once the alignment marks have been recorded an alignment image is saved at block 103, a periodicity is defined at block 105 to move between different points of interest for examination on wafer 30. At block 107, the system is aligned based on the saved alignment image and periodicity size and a user manually moves to a point of interest of an exposure field an offset distance at block ~~107~~108 and takes measurements at block 109 before moving to the next measurement location at block 111.